

AMENDMENTS TO THE CLAIMS

This listing of claims will replace all prior versions and listings of claims in the application:

LISTING OF CLAIMS:

1. (currently amended): A film-forming device with a substrate rotating mechanism, which comprises:

a susceptor in the form of a circular disk and provided at ~~the~~ an outer periphery thereof with a revolution input section;

a base plate positioned below the susceptor and rotatably retaining the susceptor;

a first rotating mechanism including at least one revolution generating section, the revolution generating section rotating the susceptor at the outer periphery of the susceptor by way of imparting a rotating force to the revolution input section;

a plurality of substrate tray retaining sections positioned circumferentially around a rotation axis of the susceptor;

a plurality of annular substrate trays provided at ~~the~~ an outer periphery thereof with a rotation input section and rotatably supported in the corresponding substrate tray retaining sections;

a second rotating mechanism including a rotation generating section, the rotation generating section rotating the substrate trays by way of imparting a rotating force to each rotation input section; and

a plurality of substrates retained in the corresponding substrate trays, the substrates being revolved by the rotation of the susceptor and rotated by the rotation of the substrate trays to apply a certain film-forming process.

2. (original): A film-forming device with a substrate rotating mechanism according to claim 1, wherein said first rotating mechanism rotatably retains the susceptor via a bearing supported between bearing grooves, each provided at the susceptor and the base plate, and wherein said second rotating mechanism rotatably retains the substrate trays via a bearing supported between bearing grooves, each provided at the substrate trays and the susceptor.

3. (original): A film-forming device with a substrate rotating mechanism according to claim 2, wherein in the first rotating mechanism, the bearing groove of said susceptor and the bearing groove of said base plate are each provided with a horizontal plane and a vertical plane, wherein the bearing groove of said susceptor supports the bearing at an upper support portion and an outer support portion, which position above the bearing and provided in said horizontal and vertical planes, and the bearing groove of the base plate supports the bearing at a lower support portion and an inner support portion, which position below the bearing and provided in said horizontal and vertical planes, and wherein said upper support portion and said lower support portion position at the uppermost position and the lowermost position of the bearing, and the outer support portion and the inner support portion position at both ends of the bearing in the horizontal direction.

4. (original): A film-forming device with a substrate rotating mechanism according to claim 1, wherein each substrate tray retains the substrate on a substrate support with a film-formation plane of the substrate positioned downward.

5. (original): A film-forming device with a substrate rotating mechanism according to claim 2, wherein each substrate tray retains the substrate on a substrate support with a film-formation plane of the substrate positioned downward.

6. (original): A film-forming device with a substrate rotating mechanism according to claim 3, wherein each substrate tray retains the substrate on a substrate support with a film-formation plane of the substrate positioned downward.

7. (original): A film-forming device with a substrate rotating mechanism according to claim 1 further comprising a temperature control mechanism for adjusting a certain area including the plurality of substrates to a desired temperature distribution, wherein the temperature control mechanism includes at least two temperature control devices, which position both above and below the susceptor or only above the susceptor.

8. (original): A film-forming device with a substrate rotating mechanism according to claim 2 further comprising a temperature control mechanism for adjusting a certain area

including the plurality of substrates to a desired temperature distribution, wherein the temperature control mechanism includes at least two temperature control devices, which position both above and below the susceptor or only above the susceptor.

9. (original): A film-forming device with a substrate rotating mechanism according to claim 4 further comprising a temperature control mechanism for adjusting a certain area including the plurality of substrates to a desired temperature distribution, wherein the temperature control mechanism includes at least two temperature control devices, which position both above and below the susceptor or only above the susceptor.

10. (original): A film-forming device with a substrate rotating mechanism according to claim 2, wherein the substrate trays, the susceptor and the bearings are made from graphite carbon.

11. (original): A film-forming device with a substrate rotating mechanism according to claim 1, wherein said susceptor is provided at a center portion with an opening, and said opening is covered by a cap member, which is made from the material selected from the group consisting of carbon (C), quartz (SiO_2), molybdenum (Mo), tungsten (W), silicon carbide (SiC), silicon (Si) and gallium arsenide (GaAs).

12. (original): A film-forming device with a substrate rotating mechanism according to claim 1, wherein said certain film-forming process is a thin-film growth by Metal Organic Chemical Vapor Deposition (MOCVD) method.

13. (original): A film-forming device with a substrate rotating mechanism according to claim 2, wherein said certain film-forming process is a thin-film growth by Metal Organic Chemical Vapor Deposition (MOCVD).

14. (original): A film-forming device with a substrate rotating mechanism according to claim 4, wherein said certain film-forming process is a thin-film growth by Metal Organic Chemical Vapor Deposition (MOCVD).

15. (original): A film-forming device with a substrate rotating mechanism according to claim 7, wherein said certain film-forming process is a thin-film growth by Metal Organic Chemical Vapor Deposition (MOCVD).

16. (original): A film-forming device with a substrate rotating mechanism according to claim 9, wherein said certain film-forming process is a thin-film growth by Metal Organic Chemical Vapor Deposition (MOCVD).

17. (new): A film-forming device with a substrate rotating mechanism according to claim 1, wherein each of the substrate trays rotates synchronously with the rotation of the susceptor.

18. (new): A film-forming device with a substrate rotating mechanism according to claim 17, wherein the revolution input section and the rotation input section are formed by gears, and wherein the rotation generating section is a ring-shaped stationary gear, the inner periphery of which is provided with gears meshing with the rotation input section of each substrate tray.

19. (new): A film-forming device with a substrate rotating mechanism, which comprises:
a susceptor in the form of a circular disk and provided at an outer periphery thereof with a revolution input section;

a base plate positioned below the susceptor and rotatably retaining the susceptor;

a first rotating mechanism including at least one revolution generating section, the revolution generating section rotating the susceptor at the outer periphery of the susceptor by way of imparting a rotating force to the revolution input section;

a plurality of substrate tray retaining sections positioned circumferentially around a rotation axis of the susceptor;

a plurality of annular substrate trays provided at an outer periphery thereof with a rotation input section and rotatably supported in the corresponding substrate tray retaining sections;

a second rotating mechanism including a rotation generating section, the rotation generating section rotating the substrate trays by way of imparting a rotating force to each rotation input section;

a plurality of substrates retained in the corresponding substrate trays, the substrates being revolved by the rotation of the susceptor and rotated by the rotation of the substrate trays to apply a certain film-forming process;

a reacting chamber extending across the rotation axis of the susceptor and surrounding the substrate tray retaining sections; and

a temperature control mechanism positioned in the reacting chamber.

20. (new): A film-forming device with a substrate rotating mechanism according to claim 19, wherein each of the substrate trays rotates synchronously with the rotation of the susceptor.

21. (new): A film-forming device with a substrate rotating mechanism according to claim 20, wherein the revolution input section and the rotation input section are formed by gears, and wherein the rotation generating section is a ring-shaped stationary gear, the inner periphery of which is provided with gears meshing with the rotation input section of each substrate tray.

22. (new): A film-forming device with a substrate rotating mechanism according to claim 19, wherein said first rotating mechanism rotatably retains the susceptor via a bearing

supported between bearing grooves, each provided at the susceptor and the base plate, and wherein said second rotating mechanism rotatably retains the substrate trays via a bearing supported between bearing grooves, each provided at the substrate trays and the susceptor.

23. (new): A film-forming device with a substrate rotating mechanism according to claim 22, wherein in the first rotating mechanism, the bearing groove of said susceptor and the bearing groove of said base plate are each provided with a horizontal plane and a vertical plane, wherein the bearing groove of said susceptor supports the bearing at an upper support portion and an outer support portion, which position above the bearing and provided in said horizontal and vertical planes, and the bearing groove of the base plate supports the bearing at a lower support portion and an inner support portion, which position below the bearing and provided in said horizontal and vertical planes, and wherein said upper support portion and said lower support portion position at the uppermost position and the lowermost position of the bearing, and the outer support portion and the inner support portion position at both ends of the bearing in the horizontal direction.

24. (new): A film-forming device with a substrate rotating mechanism according to claim 19, wherein each substrate tray retains the substrate on a substrate support with a film-formation plane of the substrate positioned downward.

25. (new): A film-forming device with a substrate rotating mechanism according to claim 22, wherein the substrate trays, the susceptor and the bearings are made from graphite carbon.

26. (new): A film-forming device with a substrate rotating mechanism according to claim 19, wherein said susceptor is provided at a center portion with an opening, and said opening is covered by a cap member, which is made from the material selected from the group consisting of carbon (C), quartz (SiO₂), molybdenum (Mo), tungsten (W), silicon carbide (SiC), silicon (Si) and gallium arsenide (GaAs).

27. (new): A film-forming device with a substrate rotating mechanism according to claim 19, wherein said certain film-forming process is a thin-film growth by Metal Organic Chemical Vapor Deposition (MOCVD) method.

28. (new): A compound semiconductor made by the film-forming device of claim 1.

29. (new): A compound semiconductor made by the film-forming device of claim 19.